Plasma/etching 1 - basic technologies

This talk will provide an overview of wet and dry etching techniques, focusing on their fundamentals and applications. We will begin with an introduction to etching and key terminologies, followed by a detailed discussion of wet etching methods, tools, and material examples. Advantages and disadvantages of wet etching will also be explored. The talk will then shift to dry etching, covering plasma and collision processes. We will examine the various sidewall profiles achievable through dry etching and explore different etching configurations. Additionally, the available dry etching tools at MNF/FBK will be introduced. Finally, a comparison of wet and dry etching will be provided, highlighting their distinct benefits and limitations.